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PATENT APPLICATION

Attorney Docket No.: 107314

AMENDMENT TRANSMITTAL

In re the Application of

Yasunaga KAYAMA

Group Art Unit: 2851

Application No.: 09/713,215

Examiner: P. B. Kim

Filed: November 16, 2000

For: EXPOSURE APPARATUS AND METHOD THAT EXPOSES A PATTERN ONTO A SUBSTRATE
(AS AMENDED)

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

Transmitted herewith is an Amendment in the above-identified application.

- ☐ Entitlement to small entity status is hereby asserted.
☐ Small entity status of this application has been established.

The filing fee has been calculated as shown below:

				SMALL ENTITY		OR	OTHER THAN A SMALL ENTITY	
(Column 1)	(Column 2)	(Column 3)		RATE	ADD'L FEE		RATE	ADD'L FEE
CLAIMS REMAINING AFTER AMENDMENT	HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA						
TOTAL CLAIMS	*44 MINUS	**41	=3	x 9	\$		x 18	\$ 54
INDEP CLAIMS	*3 MINUS	***3	=0	x 42	\$		x 84	\$
<input type="checkbox"/> FIRST PRESENTATION OF MULTIPLE DEP. CLAIM				+ 140	\$	OR	+280	\$
					\$			\$ 54

- * If the entry in Column 1 is less than the entry in Column 2, write "0" in Column 3.
** If the "Highest Number Previously Paid For" IN THIS SPACE is less than 20, write "20" in this space.
*** If the "Highest Number Previously Paid For" IN THIS SPACE is less than 3, write "3" in this space.

The "Highest Number Previously Paid For" in this space (Total or Independent) is the highest number found from the equivalent box in Column 1 of a prior Amendment or the number of claims originally filed.

- ☒ Check No. 135283 in the amount of \$54.00 is attached. The Director is hereby authorized to charge any other fees that may be required to complete this filing, or to credit any overpayment, to Deposit Account No. 15-0461. Two duplicate copies of this sheet are attached.

DEPOSIT ACCOUNT USE
AUTHORIZATION
Please grant any extension
necessary for entry;
Charge any fee due to our
Deposit Account No. 15-0461

Respectfully submitted,

Mario A. Costantino
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MAC:RZE/dmw

Date: October 11, 2002



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yasunaga KAYAMA

Application No.: 09/713,215

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For: EXPOSURE APPARATUS AND METHOD THAT EXPOSES A PATTERN ONTO A SUBSTRATE (AS AMENDED)

Group Art Unit: 2851

Examiner: P. B. Kim

Docket No.: 107314

#9/2
10-16-02
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AMENDMENT

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

RECEIVED
OCT 16 2002
TECHNOLOGY CENTER-2800

In reply to the May 15, 2002 Office Action, the shortened statutory period for reply being extended by the attached Petition for Extension of Time, please amend the above-identified application as follows:

IN THE TITLE:

Please replace the title with the following title:

--EXPOSURE APPARATUS AND METHOD THAT EXPOSES

A PATTERN ONTO A SUBSTRATE--.

IN THE CLAIMS:

Please replace claims 1, 12-14, 16, 18, 27-30 and 39-41 as follows:

1. (Amended) An exposure apparatus that exposes a pattern onto a substrate, the exposure apparatus comprising:
- a projection system to project the pattern onto the substrate;
 - a holder connected to the projection system to hold the projection system;
 - a main frame that mounts the projection system by means of the holder;